



11/3

Box AF
Expedited Procedure
Examining Group 2813 Muller
Docket No. 740819-634

1/22/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:)
Koji ARITA et al.) Group Art Unit: 2813
Application No.: 09/938,528) Examiner: David S. BLUM
Filed: 08/27/2001)
For: METHOD FOR MANUFACTURING A)
SEMICONDUCTOR DEVICE)

RECEIVED
JAN 16 2003
TECHNOLOGY CENTER 2800

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231
ATTN: **BOX AF**

Sir:

In response to the Office Action mailed September 11, 2002, the due date for which having been extended one (1) month to January 11, 2003, please amend the above identified application as follows.

IN THE CLAIMS:

Please amend claim 1 as follows:

Sub C 7 1. (Twice Amended) A method for manufacturing a semiconductor device, comprising

the steps of:

B1 forming, in a semiconductor layer formed on a first insulating film, an element isolation groove extending to the first insulating film;

depositing a second insulating film so as to partially fill the element isolation groove by using a vapor deposition method;

forming an embedded layer on the second insulating film so as to completely fill the element isolation groove; and

forming a third insulating film on the embedded layer,